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TITLE: ELECTRON CYCLOTRON RESONANCE PLASMA
CVD DEVICE

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INVENTOR-INFORMATION:

NAME

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ABSTRACT:

PURPOSE: To uniformize the density of plasma flowing into a reaction chamber and to simultaneously attain the uniformity in film thickness and homogeneity by providing an impeller to be rotated by a plasma current in the plasma current.

CONSTITUTION: A rotating stirrer 12 as the impeller is set between a plasma producing chamber 10 and the reaction chamber 30 in the electron cyclotron resonance plasma CVD device. The plasma current proceeding to the reaction



chamber 30 from the plasma producing chamber 10 collides with the blade 12b of the stirrer 12 to rotate the stirrer 12, and agitated by the rotation. The density distribution of the plasma introduced into the reaction chamber 30 is uniformized by the agitation. Since the opening 12a of the stirrer 12 is rotated and moved by the rotation of the stirrer 12, the plasma current is not shadowed, and the uniformity in the film quality is unaffected.

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